

Usage fees – NIMS Microstructural Characterization Platform
(not including consumption tax)

			Support type 1.Common use 2.Technical support 3.Technical surrogate 4. Collaborative study	Reservation per	Common use (yen/hour)			Technical support (yen/hour)			Technical surrogate & Collaborative study(yen/hour)		
					University /Public institution	smaller companies	Large companies	University /Public institution	smaller companies	Large companies	University /Public institution	smaller companies	Large companies
TEM	Real working environment physical characterization TEM (JEM-ARM200F-G)	Sengen	1,2,3,4	Session (3.5h)	4,000	8,000	12,000	6,100	12,200	18,300	6,310~	12,620~	18,930~
TEM	Real working environmental electron holography microscope	Sengen	1,2,3,4	Session (3.5h)	4,000	8,000	12,000	6,100	12,200	18,300	6,310~	12,620~	18,930~
TEM	300kV transmission electron microscope (FEI Tecnai G2 F30)	Sengen	1,2,3,4	Session (3.5h)	4,000	8,000	12,000	6,100	12,200	18,300	6,310~	12,620~	18,930~
TEM	300kV field emission transmission electron microscope (JEM-3000F)	Sengen	1,2,3,4	Session (3.5h)	3,000	6,000	9,000	5,100	10,200	15,300	5,310~	10,620~	15,930~
TEM	200kV field emission transmission electron microscope (JEM-2100F1, JEM-2100F2)	Sengen	1,2,3,4	Session (3.5h)	2,000	4,000	6,000	4,100	8,200	12,300	4,310~	8,620~	12,930~
TEM	200kV transmission electron microscope (JEM-2100)	Sengen	1,2,3,4	Session (3.5h)	1,000	2,000	3,000	3,100	6,200	9,300	3,310~	6,620~	9,930~
TEM	Field emission scanning electron microscope (JSM-7000F)	Sengen	1,2,3,4	Session (3.5h)	1,000	2,000	3,000	3,100	6,200	9,300	3,310~	6,620~	9,930~
TEM	Focused Ion Beam systems (JIB-4000, JEM-9320FIB, JEM-9310FIB1, JEM-	Sengen	1,2,3,4	Session (3.5h)	1,000	2,000	3,000	3,100	6,200	9,300	3,310~	6,620~	9,930~
TEM	Dual beam system(NB5000)	Sengen	1,2,3,4	Session (3.5h)	3,000	6,000	9,000	5,100	10,200	15,300	5,310~	10,620~	15,930~
TEM	Pickup system	Sengen	1,2,3,4	Hour(1h)	1,000	2,000	3,000	3,100	6,200	9,300	3,310~	6,620~	9,930~
TEM	TEM sample preparation apparatus	Sengen	1,2,3,4	Hour(1h)	1,000	2,000	3,000	3,100	6,200	9,300	3,310~	6,620~	9,930~
TEM	Ultramicrotome (Leica EM UC6)	Sengen	2,3,4	Hour(1h)				3,100	6,200	9,300	3,310~	6,620~	9,930~
TEM	HRTEM Analysis system	Sengen	2,3,4	Hour(1h)				3,100	6,200	9,300	3,310~	6,620~	9,930~
TEM	Electron tomography analysis system	Sengen	2,3,4	Hour(1h)				3,100	6,200	9,300	3,310~	6,620~	9,930~
TEM	Atom-discriminating electron microscope (JEM-3100FEF)	Namiki	1,2,3,4	Hour(1h)	4,000	8,000	12,000	5,500	11,000	16,500	7,000	14,000	21,000
TEM	Cold-FEG Lorentz Microscope (HF-3000L)	Namiki	1,2,3,4	Session (3.5h)	2,000	4,000	6,000	4,100	8,200	12,300	4,310~	8,620~	12,930~
TEM	Cold-FEG Transmission Electron Microscope (HF-3000S)	Namiki	1,2,3,4	Session (3.5h)	2,000	4,000	6,000	4,100	8,200	12,300	4,310~	8,620~	12,930~
TEM	Atomic-resolution analytical electron microscope(FEI Titan Cubed)	Namiki	1,2,3,4	Session (3.5h)	4,000	8,000	12,000	6,100	12,200	18,300	6,310~	12,620~	18,930~
TEM	Ceramics sample preparation facilities	Namiki	3,4	Session (3.5h)							3,310~	6,620~	9,930~
TEM	Damage-free TEM Sample Milling Apparatus (NanoMill Model1040)	Namiki	1,2,3,4	Hour(1h)	1,000	2,000	3,000	2,500	5,000	7,500	4,000	8,000	12,000

« Technical support »	University Public institution	smaller companies	Large companies
Technical guidance fee	2,100	4,200	6,300

« Technical surrogate (NIMS staff selects and operates the equipment) »	University Public institution	smaller companies	Large companies
TEM sample preparation	3,310~	6,620~	9,930~
TEM observation	4,310~	8,620~	12,930~
Data analysis	2,100	4,200	6,300

※This is ailable only for technical surrogate of TEM.

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SPM	Scanning tunneling microscope with magnet(VLT-STM)	Sengen	2,3,4	Day(8h)				2,500	5,000	7,500	5,500	11,000	16,500
SPM	Scanning Tunneling microscope (LT-STM)	Sengen	2,3,4	Day(8h)				2,500	5,000	7,500	3,250~	6,500~	9,750~
SPM	Environment-Control Frequency-Modulation Scanning Probe Microscope (FM-SPM)	Sengen	1,2,3,4	Day(8h)	1,000	2,000	3,000	2,500	5,000	7,500	2,650~	5,300~	7,950~
Surface Electron Microscopy	Spin-polarized low energy electron microscope (SPLEEM)	Sengen	3,4	Day(8h)							6,000~	12,000~	18,000~
He Ion Microscope	Scanning helium ion microscope (ORION Plus)	Sengen	2,3,4	Hour(1h)	2,000			5,500	11,000	16,500	5,800~	11,600~	17,400~
NMR	500 MHz Solid-State NMR (I) (NMR500 (I))	Sakura	1,2,3,4	Day(8h)	1,000	2,000	3,000	2,500	5,000	7,500	2,650~	5,300~	7,950~
NMR	500 MHz Solid-State NMR (II) (NMR500 (II))	Sakura	1,2,3,4	Day(8h)	1,000	2,000	3,000	2,500	5,000	7,500	2,650~	5,300~	7,950~
NMR	800MHz Solid-State High-resolution NMR (NMR800)	Sakura	1,2,3,4	Day(8h)	1,000	2,000	3,000	2,500	5,000	7,500	2,650~	5,300~	7,950~
SPring-8	Hard X-ray Photoelectron Spectrometer	Harima	3,4	Shift(8h)							2,650~	5,300~	7,950~
SPring-8	High-resolution X-ray powder diffractometer	Harima	3,4	Shift(8h)							2,650~	5,300~	7,950~
SPring-8	8-axis diffractometer for structural analysis of functional thin films	Harima	3,4	Shift(8h)							2,650~	5,300~	7,950~
SPring-8	Hard X-ray Photoelectron Spectrometer with Automatic Sample Changer	Harima	3,4	Shift(8h)							2,650~	5,300~	7,950~
3D imaging	Versatile triple-beam scanning electron microscope(SMF-1000)	Sengen	1,2,3,4	Hour(1h)	3,000	6,000	9,000	4,500	9,000	13,500	6,750~	13,500~	20,250~
3D imaging	High resolution X-ray CT device with micro X-ray source (0.4 μm) (SMX-160CTS)	Sengen	1,2,3,4	Hour(1h)	1,000	2,000	3,000	2,500	5,000	7,500	4,750	9,500	14,250
Surface Analysis	Time-of-Flight Secondary Ion Mass Spectrometry (PHI TRIFT V nanoTOF)	Sengen	3,4	Hour(1h)	1,500						6,000~	12,000~	18000~
Surface Analysis	Field Emission Electron Probe Micro-Analyzer(JXA-8500F)	Sengen	1,2,3,4	Hour(1h)	2,000	4,000	6,000	3,500	7,000	10,500	5,000~	10,000~	15,000~
Surface Analysis	Scanning Auger electron Microprobe (PHI 680)	Sengen	1,2,3,4	Hour(1h)	2,000	4,000	6,000	3,500	7,000	10,500	5,000~	10,000~	15,000~
Surface Analysis	BELSORP-HP/BELSORP-max	Sengen	1,2,3,4	Hour(1h)	1,000	2,000	3,000	2,500	5,000	7,500	4,000	8,000	12,000

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